

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q87054

Yasuki KIMURA

Appln. No.: 10/529,152

Group Art Unit: 1763

Confirmation No.: 1832

Examiner: Allan W. Olsen

Filed: March 24, 2005

For: METHOD OF ETCHING CHROMIUM THIN FILM AND METHOD OF PRODUCING  
PHOTOMASK

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated November 21, 2006, please amend the above-identified application as follows on the accompanying pages.

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